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CERTIFICATE OF MAILING UNDER 37 C.F.R. §1.8

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail, with sufficient postage, in an envelope addressed to: Commissioner for Patents, P. O. Box 1450, Alexandria, VA 22313-1450, on the below date:
Date: February 27, 2007 Name: Jasper W. Dockrey Signature:

**BRINKS
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& LIONE**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Appln. of: Moriceau et al.

Appln. No.: 10/565,621

Filed: July 25, 2006

For: Stacked Structure and Production Method
Thereof

Attorney Docket No: 9905/37 (BIF116044US)

Examiner: Not yet assigned

Art Unit: 2812

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

TRANSMITTAL

Sir:

Attached is/are:

Supplemental Information Disclosure Statement; three references; Form PTO-1449.
 Return Receipt Postcard

Fee calculation:

No additional fee is required.
 Small Entity.
 An extension fee in an amount of \$____ for a ____-month extension of time under 37 C.F.R. § 1.136(a).
 A petition or processing fee in an amount of \$____ under 37 C.F.R. § 1.17(____).
 An additional filing fee has been calculated as shown below:

	Claims Remaining After Amendment		Highest No. Previously Paid For	Present Extra	Small Entity		Not a Small Entity		
					Rate	Add'l Fee	or	Rate	Add'l Fee
Total		Minus			x \$25=			x \$50=	
Indep.		Minus			x 100=			x \$200=	
First Presentation of Multiple Dep. Claim					+\$180=			+\$360=	
					Total	\$		Total	\$

Fee payment:

A check in the amount of \$____ is enclosed.
 Please charge Deposit Account No. 23-1925 in the amount of \$____. A copy of this Transmittal is enclosed for this purpose.
 Payment by credit card in the amount of \$____ (Form PTO-2038 is attached).
 The Director is hereby authorized to charge payment of any additional filing fees required under 37 CFR § 1.16 and any patent application processing fees under 37 CFR § 1.17 associated with this paper (including any extension fee required to ensure that this paper is timely filed), or to credit any overpayment, to Deposit Account No. 23-1925.

Respectfully submitted,

Jasper W. Dockrey (Reg. No. 33,888)

February 27, 2007
Date

BRINKS HOFER GILSON & LIONE
NBC Tower – Suite 3600, 455 N. Cityfront Plaza Drive, Chicago, IL 60611-5599

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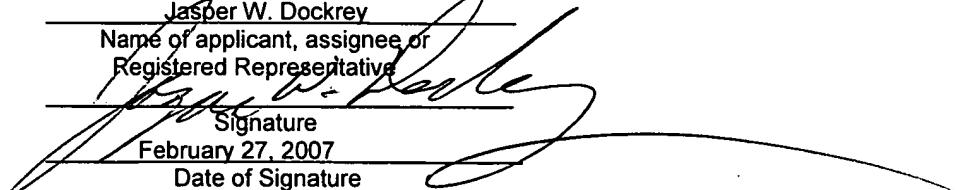
on

February 27, 2007

Date of Deposit

Jasper W. Dockrey

Name of applicant, assignee or
Registered Representative

Signature

February 27, 2007

Date of Signature

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

This application claims priority under 35 USC §120 to the following United States patent applications: 371 of PCT/FR04/01858 97/15/2004; FR 0308865, filed July 21, 2003. In accordance with 37 C.F.R. §1.98(d), the Examiner is directed to the references cited in all Information Disclosure Statements filed in the priority United States patent applications cited above in addition to the references cited herein.

In accordance with the duty of disclosure under 37 C.F.R. §1.56 and §§1.97-1.98, and more particularly in accordance with 37 C.F.R. §1.97(b), Applicants hereby cite the following reference(s):

FOREIGN DOCUMENTS

DOCUMENT NUMBER Number-Kind Code (if known)	DATE	COUNTRY
95 08882	July 21, 1995	France (English abstract attached)

OTHER DOCUMENTS

Fujitsuka et al., "A new processing technique to prevent stiction using silicon selective etching for SOT-MEMS", Sensors and Actuators, A97-98, pp. 716-719, 2002
Ashurst et al., "Wafer level anti-stiction coatings for MEMS", Sensors and Actuators A104, pp. 213-221, 2003

Applicants are enclosing Form PTO-1449 (one sheet), along with a copy of each listed reference for which a copy is required under 37 C.F.R. §1.98(a)(2).

The Applicants provide herewith a non-certified English translation of the technical domain section of French patent application no. 95-08882. This application was cited during prosecution of the corresponding European patent application and describes a process for forming a micromechanical structure in which a sacrificial layer (110) is removed leaving a useful layer (120) that can function, for example, as a seismic mass (220) in an accelerometer (FIGs. 7 and 8).

As each of the non-patent documents are published in English, no further commentary is believed to be necessary, 37 C.F.R §1.98(a)(3). Applicants respectfully request the Examiner's consideration of the above reference(s) and entry thereof into the record of this application.

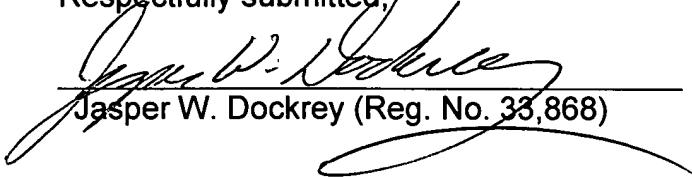
By submitting this Statement, Applicants are attempting to fully comply with the duty of candor and good faith mandated by 37 C.F.R. §1.56. As such, this Statement is not intended to constitute an admission that any of the enclosed references, or other information referred to therein, constitutes "prior art" or is otherwise "material to patentability," as that phrase is defined in 37 C.F.R. §1.56(a).

Applicants have calculated no fee to be due in connection with the filing of this Statement. However, the Director is authorized to charge any fee deficiency associated with the filing of this Statement to a deposit account, as authorized in the Transmittal accompanying this Statement.

Respectfully submitted,

February 27, 2007

Date


Jasper W. Dockrey (Reg. No. 33,868)



FORM PTO-1449	SERIAL NO. 10/565,621	CASE NO. 9905/37 (BIF116044/US)
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT	FILING DATE July 25, 2006	GROUP ART UNIT 2812
(use several sheets if necessary)	APPLICANT(S): Moriceau et al.	

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER <small>Number-Kind Code (if known)</small>	DATE	COUNTRY	CLASS/ SUBCLASS	TRANSLATION YES OR NO
B1	95 08882	July 21, 1995	France		Yes abstract only

EXAMINER INITIAL	OTHER ART – NON PATENT LITERATURE DOCUMENTS <small>(Include name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.)</small>	
	B2	Fujitsuka et al., "A new processing technique to prevent stiction using silicon selective etching for SOT-MEMS", Sensors and Actuators, A97-98, pp. 716-719, 2002
	B3	Ashurst et al., "Wafer level anti-stiction coatings for MEMS", Sensors and Actuators A104, pp. 213-221, 2003
	B4	
	B5	
	B6	
	B7	

EXAMINER	DATE CONSIDERED
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.